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Substitute for form 1449B/PTO				<i>Complete if Known</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/599,106
				Filing Date	09/19/2006
				First Named Inventor	Ji Zhu
				Art Unit	2812
				Examiner Name	Unknown
(Use as many sheets as necessary)				Attorney Docket Number	IB-1997
Sheet	1	of	1		

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		SONEK, ET AL., "Ultraviolet Grating Polarizers," Journal of Vacuum Science Technology, Vol. 19 (No. 4), p. 921-923, (August 17, 1981).	
		FLANDERS, ET AL., "Application of \checkmark 100 Å Linewidth Structures Fabricated by Shadowing Techniques a)," Journal of Vacuum Science Technology, Vol. 19 (No. 4), p. 892-896, (November/December 1981).	
		CUI, ET AL., "Large Area 50 nm Period Grating by Multiple Nanoimprint Lithography and Spatial Frequency Doubling," Applied Physics Letters, Vol. 90, p. 043118-1-043118-3, (October 5, 2006).	
		FLANDERS, ET AL., "Generation of <50 nm Period Gratings Using Edge Defined Techniques," Journal of Vacuum Science & Technology B, Vol. 1 (No. 4), p. 1105-1108, (August 29, 1983).	
		JOHNSON, ET AL., "Generation of Surface Gratings with Periods < 1000 Å," Applied Physics Letters, Vol. 38 (No. 7), p. 532-534, (January 13, 1981).	
		Yu, ET AL., "Fabrication of Large Area 100 nm Pitch Grating by Spatial Frequency Doubling and Nanoimprint Lithography for Subwavelength Optical Applications," Journal of Vacuum Technology B, Vol. 19 (No. 6), p. 2816-2819, (August 6, 2001).	

Examiner Signature	/Allan Olsen/	Date Considered	12/15/2010
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). **2** Applicant is to place a check mark here if English language Translation is attached.

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ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /A.O./